



# R&D on Sapphire Mirrors for the Einstein Telescope Low-Frequency Detector

## Einstein Telescope France Workshop

Severin Nadji reporting for LMA – IP2I and iLM  
Laboratoire des Matériaux Avancées de Lyon

April 1, 2026

## 1. Updates on substrates for ET

- 1.1 ET HF: Fused silica
- 1.2 ET-LF: Silicon

## 2. Sapphire mirrors for ET LF

- 2.1 Sapphire crystal growth in Lyon
- 2.2 Sapphire polishing in Lyon

## 3. Implementation of birefringence effects in OSCAR

## 4. Summary and outlook

## ET-HF: Fused silica

### Fused silica is the baseline for ET-HF

- Mechanical and optical properties ✓

### Mirror limitation: Coating Thermal Noise (CTN)

- ET HF target:  $\sim 4\times$  lower than in aLIGO

#### 💡 CTN mitigation: post-deposition annealing

**$T \leq 600^\circ\text{C}$  – for aVirgo/aLigo [1] ✓**

- Works well in reducing the CTN

**$T > 600^\circ\text{C}$  – for aLigo O5 ✗**

- Surface figure degradation
- Substrate absorption/birefringence ↗

## ET-LF

### Requirements

- Low optical absorption
  - Critical for ITMs to avoid heating cryogenic mirrors
  - Absorption target below  $<10$  ppm/cm
- Large size:  $>45$  cm,  $\sim 200$  kg
  - To reduce coating thermal noise
  - To reduce radiation pressure noise

**Main issue: High purity material of this size is currently not available**

More details: MAD 2025 - Introduction on Substrate Research

## ET-LF: Silicon

### Current state

Method	Absorption	Key Characteristics
Float-Zone (FZ)	< 10 ppm/cm	High purity, Limited $\varnothing$ (currently 200 mm) <i>Projection: 300 mm expected by 2028, 400 mm over 5 years</i> MAD 2025 - Contribution ID: 63
Czochralski (Cz)	Medium	High impurities, Large $\varnothing$ achievable (300–500 mm)
DS/QM [2]	High	Even higher impurities, Larger $\varnothing$ achievable ( $\geq 500$ mm)

\* DS = Directional Solidification, QM = Quasi-Monocrystalline

More details: MAD 2025 - Contribution ID: 63, ET-0456A-25

### Summary

- No single method currently meets all ET-LF requirements
- Hybrid approaches: composite test mass (see MAD 2025 - Contribution ID: 56)

## Motivation

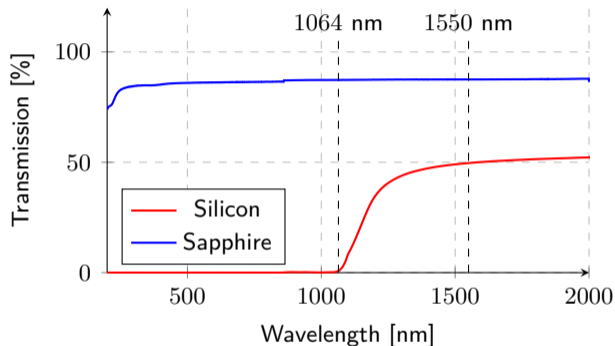


Figure 1: Sapphire[3] and Silicon[4] transmission plots

### Better optical transmission from visible to near-infrared

- Well established  $\lambda = 1064$  nm technology, a significant advantage

Is it possible to grow sapphire crystals with low or controlled absorption and birefringence?

More details can be found in ET-0469A-25

## Sapphire crystal growth in Lyon

Controlled absorption on  $\varnothing 30$  mm samples (from T. Aventin PhD thesis)

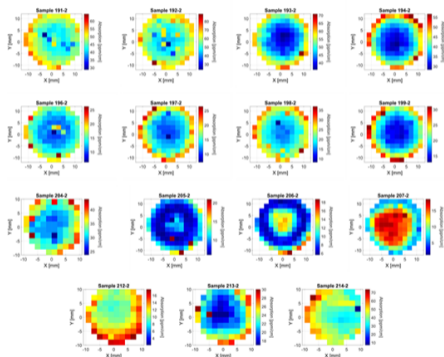
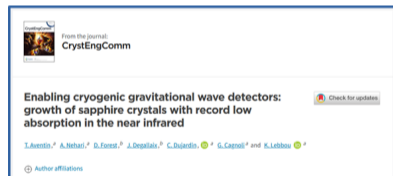


Figure 2: Absorption maps of sapphire crystals for different growth parameters [5]

- Absorption below  $15 \text{ ppm}\cdot\text{cm}^{-1}$
- Birefringence reduction/uniformity being studied



**News from KAGRA [LIGO-G2502021]:**  
Sapphire crystals with  $10\times$  better  
birefringence homogeneity were found

## Sapphire crystal growth in Lyon

### Growing large ingots



Figure 3: Growth furnace for large sapphire crystals

**Sapphire bulk of  $\varnothing 360$  mm already produced with Cz method!**

- Commissioning of the growth furnace
- Scaled to grow  $\varnothing 450$  mm ingots



*K. Lebbou and A. Nehari*

## Sapphire polishing in Lyon

Seven axis CNC optical polishing machine installed in fall 2024



Figure 4: Zeeko polishing machine at the LMA

- Chemical-mechanical polishing machine
- Up to  $\varnothing 400$  mm,  $m=50$  kg
- Compatible with other materials
- Site acceptance tests done
- Commissioning on going...



More details can be found in ET-0469A-25

## Sapphire polishing in Lyon: $\varnothing 100$ mm

### Flatness correction – Preliminary results

- Results surpassed expectations
  - $PV \simeq \lambda/60$ , for  $\varnothing 50$  mm
  - $PV \simeq \lambda/12$ , for  $\varnothing 90$  mm
- Many iterations, but reducible
- Did we reach the limits of the machine?
- Next step, ion beam figuring!

Figure 5: Measured PV after successive polishing iterations

**Very good workflow polishing  $\iff$  metrology at the LMA**

## Sapphire polishing in Lyon: $\varnothing 100$ mm

### Roughness correction – Preliminary results

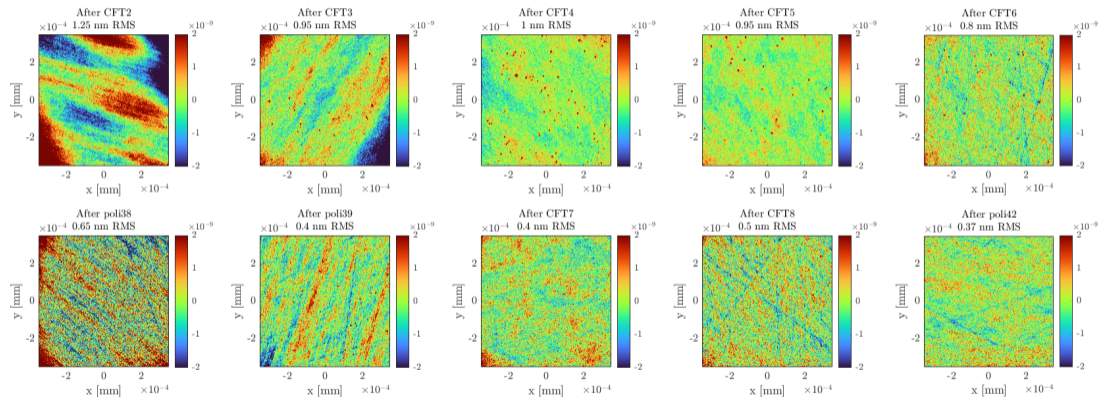


Figure 6: Roughness maps after the specified polishing iterations

## Propagation of polarised light in birefringent media

The OSCAR upgrade will account for:

- Arbitrary incident polarization – s and/or p
- Arbitrary angle of incidence –  $(\theta, \phi)$
- Arbitrary c-axis orientation –  $\phi_c(x, y)$
- Birefringence magnitude maps –  $\Delta n(x, y)$
- Fast axis orientation maps –  $\rho(x, y)$

Accurate computation of  $t_{s,p}(x, y)$  and  $r_{s,p}(x, y)$  for any birefringent plate

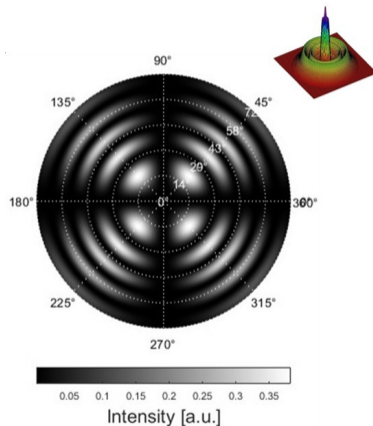


Figure 7: Computed conoscopic pattern of a c-plate between crossed polarisers

## Development updates

### Towards defining the birefringence requirements of ET LF

- New MATLAB birefringence functions developed
  - Transmission, Reflection, and Propagation
  - Being adjusted for OSCAR scripting
- OSCAR being updated to support s and p pol.

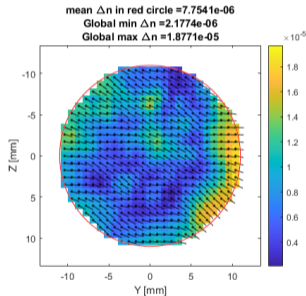
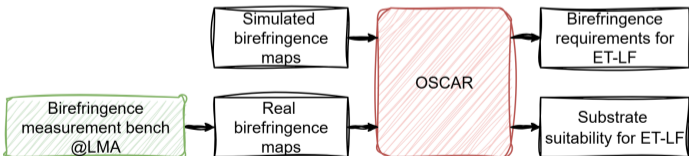


Figure 8: Example of birefringence map.

## Substrates for ET

- ET-HF: Silica substrates can't handle high-temp annealing for CTN reduction
- ET-LF: High purity silicon/sapphire ET-scale substrates are not yet available

## Sapphire polishing (LMA and IP2I)

- Polishing larger sapphire substrates:  $\varnothing 200$  mm and  $\varnothing 300$  mm
- Polishing of the barrel and flats

## Birefringence characterisation and modelling (LMA)






- Measuring the birefringence on upto  $\varnothing 450$  mm sapphire substrates
- Using OSCAR to set birefringence requirements and verify substrate suitability for ET

# MAD26 in Lyon! Save the date :)

Next Materials for Advanced Detectors workshop in Lyon, 12-14 october 2026



- LMA Lab tour: the famous "Grand coater", the polishing machine, the sapphire growth furnace, etc.

-  M. Granata, A. Amato, G. Cagnoli, M. Coulon, J. Degallaix, D. Forest, L. Mereni, C. Michel, L. Pinard, B. Sassolas, *et al.*, “Progress in the measurement and reduction of thermal noise in optical coatings for gravitational-wave detectors,” *Applied optics*, vol. 59, no. 5, pp. A229–A235, 2020.
-  F. M. Kiessling, P. G. Murray, M. Kinley-Hanlon, I. Buchovska, T. K. Ervik, V. Graham, J. Hough, R. Johnston, M. Pietsch, S. Rowan, *et al.*, “Quasi-monocrystalline silicon for low-noise end mirrors in cryogenic gravitational-wave detectors,” *Physical review research*, vol. 4, no. 4, p. 043043, 2022.
-  Thorlabs, “Transmission of uncoated sapphire. measurement at normal incidence of the total transmission of our 5 mm thick uncoated sapphire window.”
-  Thorlabs, “Transmission of uncoated silicon. measurement at normal incidence of the total transmission of our 5 mm thick uncoated sapphire window.”
-  T. Aventin, *Development of very low optical absorption sapphire substrates for the cryogenic gravitational wave detector mirrors*.  
PhD thesis, Université Claude Bernard-Lyon I, 2024.

# Thank you for your attention!

## Questions?



## Sapphire crystal growth in Lyon

### Monocrystalline fibres and ribbons (micro-pulling down method)



- Different geometries with good surface quality
- Up to 1 m long fibres, with  $\varnothing 3$  mm
- Better cooling, higher tensile strength for suspensions

## Example: sapphire (a-plate) half wave plate

$$\left\{ \begin{array}{l} n_o = 1.7680 \\ \Delta n_{x,y} = -0.008 \pm 10^{-5} \\ \phi_{c_{x,y}} = \frac{\pi}{4} \pm 10^\circ \\ \lambda = 1064 \text{ nm} \\ d = \frac{\lambda}{2\Delta n} \end{array} \right.$$

